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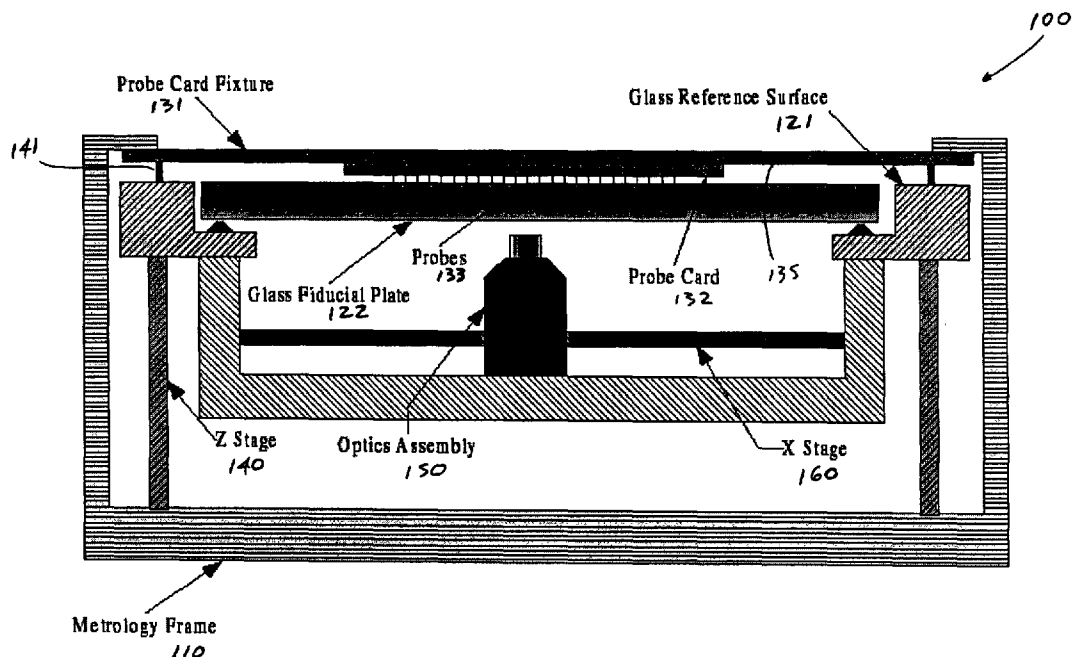
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(54) Title: METHOD OF MITIGATING EFFECTS OF COMPONENT DEFLECTION IN A PROBE CARD ANALYZER



(57) Abstract: A system and method of mitigating the effects of component deflections in a probe card analyzer system may im-
plement three-dimensional comparative optical metrology techniques to model deflection characteristics. An exemplary system
and method combine non-bussed electrical planarity measurements with fast optical planarity measurements to produce "effectively
loaded" planarity measurements.

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